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Client/Matter No. 81848.0016.001  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/546,174	Confirmation No.: 4793
Application of: Chih-Chien Liu, Ta-Shan Tseng, W. B. Shieh, J. Y. Wu, Water Lur and Shih-Wei Sun	Customer No.: 25235
Filed: April 11, 2000	
Art Unit: 1711	
Examiner: Sergent, Rabon A.	
Attorney Docket No. UMC-96-279 CON	
For: HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	

PETITION FOR WITHDRAWAL FROM ISSUE UNDER 37 CFR 1.313

MAIL STOP PETITIONS  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is a Petition for the Withdrawal from Issuance of Patent Application No. 09/546,174 under 37 CFR 1.313 to permit consideration of newly discovered art in an information disclosure statement. An RCE filing accompanies this petition. The Issue Fee was timely paid on May 17, 2004 but no patent number has been issued to date.

The Petition fee of \$130 is enclosed with this transmittal. No further fee is believed to be required by this Petition. However, should any fee be required, please charge Deposit Account No. 50-1123.

Dated: 10/25, 2004

  
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